L Number	Hits	Search Text	DB	Time stamp
2	127	(micro$needle$2 micro$hypodermic$2) and (($1mu$1m) with (long length width wide diameter))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/05/10 17:35
3	144	(etching etch etched) with silicon with tolerance	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/05/10 16:10
16	33	(etch$3 etch etched) with silicon with (micron micrometer) with ("+ / -" "+/-" tolerance)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/05/10 16:49
17	1	(etch$3 etch etched) with ((silicon with nitride) (potassium hydroxide)) with (micron micrometer) with ("+ / -" "+/-")	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/05/10 16:55
18	63	(etch$3 etch etched) same ((silicon with nitride) (potassium hydroxide)) same tolerance same (micrometer "+ / -" "+/-" micron)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/05/10 16:56
19	111	(etch$3 etch etched) same (silicon with nitride) same (potassium hydroxide) same (tolerance micron "+ / -" "+/-" micrometer)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/05/10 17:07
23	80	((sampl$3 collect$3 collection) with (micro$needle$2 micro$hypodermic$2 needle hypodermic)) same (($1mu$1m micron micrometer "1 millimeter" "one millimeter") with (long length))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/05/10 18:23
24	176	((sampl$3 collect$3 collection) with (micro$needle$2 micro$hypodermic$2 needle hypodermic)) and ((micro$needle$2 micro$hypodermic$2 needle hypodermic) same (($1mu$1m micron micrometer "1 millimeter" "one millimeter") with (long length)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/05/10 18:27